

Amendments to the Claims: This listing of claims will replace all prior versions, and listings, of claims in the application.

Listing of Claims:

1. - 28. (Canceled)

29. (Currently Amended) A head support mechanism, including:

a slider having a magnetic-head attached thereto, for recording data to and/or reproducing data from a magnetic-disk;

a slider holding plate for holding the slider;

a pair of substrates each having a piezoelectric element attached thereto;

elastic hinges for connecting the slider holding plate and the pair of substrates; and

a dimple for supporting the slider holding plate such that the slider holding plate is ~~rotatable in all directions~~ rotated in a pitch direction, a roll direction, and a yaw direction,

~~wherein the slider is rotated around said dimple by a small amount of in the yaw direction by contraction and/or expansion of at least one of the piezoelectric elements; and wherein the position of said the dimple either coincides with the center of gravity of a portion including said the slider holding plate and said the slider which is rotatable by a small amount around said the dimple as a rotating axis, or is located between the center of gravity of said the portion and said the head.~~

30. (Canceled)

31. (Currently Amended) A head support mechanism according to claim 29, wherein each of the pair of piezoelectric elements is stacked on the corresponding substrate and at least one of the pair of substrates is bent by a bimorph effect accompanying the contraction and/or expansion of at least one of the piezoelectric elements, so as to rotate the slider holding plate by a small amount.

32. (Currently Amended) A head support mechanism according to claim 29, wherein ~~said~~the dimple is provided in a tip portion of a load beam for supporting the slider holding plate.

33. (Previously Presented) A head support mechanism according to claim 31, wherein the load beam includes a pair of regulation portions for regulating the rotation of the slider holding plate.

34. (Currently Amended) A head support mechanism according to claim 29, wherein root portions of the pair of substrates ~~of said substrate~~ are integrally formed.

35. (Previously Presented) A head support mechanism according to claim 29, wherein the pair of substrates and the elastic hinges are formed of an identical material.

36. (Currently Amended) A head support mechanism according to claim 29, wherein:

the slider has an air bearing surface so as to face the magnetic disk, the air bearing surface forms an air lubricating film between the magnetic disk and the slider while the magnetic disk is rotating, and the slider is rotated around a center position of the air bearing surface by the contraction and/or expansion of at least one of the piezoelectric elements.

37. (Previously Presented) A head support mechanism according to claim 29, wherein the pair of substrates and the piezoelectric elements are coated with resin so as to be integrated together.

38. (Currently Amended) A head support mechanism according to claim 29, wherein the pair of substrates and the elastic hinges have a conductor pattern for transferring a recording signal and a reproduction signal to and from the magnetic head attached thereto.

39. (Currently Amended) A head support mechanism, comprising:

a slider having a magnetic head attached thereto, for recording data to and/or reproducing data from a magnetic disk;

a substrate having a slider support portion, a pair of transformation operation portions, and a pair of elastic hinge portions for connecting the slider support portion and the pair of transformation operation portions, respectively;

a slider holding plate for holding the slider via the slider support portion of the substrate;

a pair of piezoelectric elements each respectively mounted on the pair of transformation operation portions of saidthe substrate; and

a load beam for supporting the slider holding plate via a dimple provided in a tip portion thereof, such that the slider holding plate is rotatable in all directionsrotated in a pitch direction, a roll direction, and a yaw direction,

wherein the slider is rotated around the dimple by a small amount in the yaw direction by contraction and/or expansion of at least one of the piezoelectric elements; and wherein the position of saidthe dimple either coincides with the center of gravity of a portion including saidthe slider holding plate and saidthe slider which is rotatable by a small amount around saidthe dimple as a rotating axis, or is located between the center of gravity of saidthe portion and saidthe head.

40. (Canceled)

41. (Currently Amended) A head support mechanism according to claim 39, wherein each of the pair of piezoelectric elements is stacked on the corresponding conductor substrate portion transformation operation portion of the substrate, and at least one of the pair of conductor substrate portions transformation operation portions is bent by a bimorph effect accompanying the contraction and/or expansion of at least one of the piezoelectric elements, so as to rotate the slider holding plate by a small amount.

42. (Currently Amended) A head support mechanism according to claim 39, wherein root portions of the pair of conductor substrate portions transformation operation portions of said the substrate are integrally formed.

43. (Currently Amended) A head support mechanism according to claim 39, wherein:

the slider has an air bearing surface so as to face the magnetic disk, the air bearing surface forms an air lubricating film between the magnetic disk and the slider while the magnetic disk is rotating, and the slider is rotated around a center position of the air bearing surface by the contraction and/or expansion of at least one of the piezoelectric elements.

44. (Previously Presented) A head support mechanism according to claim 39, wherein the load beam includes a pair of regulation portions for regulating the rotation of the slider holding plate.

45. (Currently Amended) A head support mechanism according to claim 39, wherein the pair of conductor substrate portions transformation operation portions of the substrate and the piezoelectric elements are coated with resin so as to be integrated together.

46. (Currently Amended) A head support mechanism according to claim 39, wherein the pair of conductor substrate portions transformation operation portions and the pair of elastic hinge portions have a conductor pattern for transferring a recording signal and a reproduction signal to and from the magnetic head attached thereto.